



AF/IFW

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application of

Eiji HASEGAWA

Date: April 10, 2006

Serial No.: 10/768,611

Group Art Unit: 2823

Filed: January 29, 2004

Examiner: Fernando L. TOLEDO

For: SEMICONDUCTOR DEVICE WITH NITROGEN IN OXIDE FILM ON  
SEMICONDUCTOR SUBSTRATE AND METHOD OF MANUFACTURING  
THE SAME

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**RESPONSE AFTER FINAL REJECTION**  
**REQUEST FOR RECONSIDERATION**

Sir:

This is a response to the Office Action mailed January 10, 2006 in the above-identified application. Reconsideration of the application is respectfully requested.

**FEE CALCULATION**

In the event the actual fee is greater than the payment submitted or is inadvertently not enclosed or if any additional fee during the prosecution of this application is not paid, the Patent Office is authorized to charge the underpayment to Deposit Account No. 15-0700.

**CONTINGENT EXTENSION REQUEST**

If this communication is filed after the shortened statutory time period had elapsed and no separate Petition is enclosed, the Commissioner of Patents and Trademarks is petitioned, under 37 C.F.R. § 1.136(a), to extend the time for filing a response to the outstanding Office Action by the number of months which will avoid abandonment under 37 C.F.R. § 1.135. The fee under 37 C.F.R. § 1.17 should be charged to our Deposit Account No. 15-0700.

OK TO ENTER  
MMD